

Denumirea bunurilor	Modelul articulului ui	Țara de origine	Produ- cătorul	Specificarea tehnică deplină solicitată de către autoritatea contractantă	Specificarea tehnică deplină propusă de către ofertant	Standarde de referință
2	3	4	5	6	7	8
Bunuri						
Lotul 1						
1. Microscop cu lumină polarizant ă – 1 unitate	LV100N POL	Japonia	Nikon	<u>Caracteristici:</u> Sistem optic: infinit si distanta parfocala de 60 mm;	<u>Caracteristici:</u> Sistem optic: infinit si distanta parfocala de 60 mm;	Brosura Eclipse LV100N POL, pagina 2, CFI 60 -TU Plan Fluor EPI P
				- Iluminare: - lampă cu halogen de 12V/50W; - transformator de curent continuu de 12V/50W încorporat; - comutare între iluminare episcopică/diascopică; - prevazut cu lentile de tip Fly-Eye sau echivalent; filtru de balanc culoare neutra cu indice 11, Filtre densitate neutra cu indice 8 încorporate;	- Iluminare: - lampă cu halogen de 12V/50W; - transformator de curent continuu de 12V/50W încorporat; - comutare între iluminare episcopică/diascopică; - prevazut cu lentile de tip Fly-Eye sau echivalent; filtru de balanc culoare neutra cu indice 11, Filtre densitate neutra cu indice 8 încorporate;	Brosura Eclipse LV100N POL, pagina 4, 50W Halogen - Fly- Eye lens

				• Focalizare: - buton dublu de focalizare grosieră/fină; - cursa de focalizare: 30mm; - grosieră: 14mm/rotație; - fină: 0,1 mm/rotație; - increment minim: 1 μm;	• Focalizare: - buton dublu de focalizare grosieră/fină; - cursa de focalizare: 30mm; - grosieră: 14mm/rotație; - fină: 0,1 mm/rotație; - increment de 1 μm;	Brosura Eclipse LV100N POL, pagina 8, rand: Focusing
				• Ocular: cu magnificare de 15x;	Ocular: cu magnificare de 15x;	Brosura Eclipse LV100N POL, pagina 8, rand: Eyepieces
				• Tuburi oculare: trinocular pentru microscopie polarizată;	Tuburi oculare: trinocular pentru microscopie polarizată;	Brosura Eclipse LV100N POL, pagina 8, rand: Tubes
				• Tub intermediar: - lentila Bertrand incorporată cu focalizare; - comutare între observare conoscopică și ortoscopică; - analizor incorporat;	• Tub intermediar: - lentila Bertrand incorporată cu focalizare; - comutare între observare conoscopică și ortoscopică; - analizor incorporat;	Brosura Eclipse LV100N POL, pagina 8, rand: Intermediate tube
				• Analizor: Cu cadran rotativ 360°; Unghiul minim de citire de 0,1°;	Analizor: Cu cadran rotativ 360°; Unghiul de citire de 0,1°;	Brosura Eclipse LV100N POL, pagina 8, rand: Alalyzer
				• Port-obiectiv: Port-obiectiv cu cinci poziții (detașabil); Slot DIN;	Port-obiectiv: Port-obiectiv cu cinci poziții (detașabil); Slot DIN;	Brosura Eclipse LV100N POL, pagina 8, rand: Nosepiece
				• Masa: - masa circulara rotativa 360°, poate fi blocata la o anumita poziție. - incrementare de 1° și oprire la fiecare 45°; - masa mecanică atașabilă: 35 x 25mm;	• Masa: - masa circulara rotativa 360°, poate fi blocata la o anumita poziție. - incrementare de 1° și oprire la fiecare 45°; - masa mecanică atașabilă: 35 x 25mm;	Brosura Eclipse LV100N POL, pagina 8, rand: Stage
				•	•	

			Condensator: Condensator dedicat de tip swing-out; P Achromat cu apertura numerica de 0.9;	Condensator: Condensator dedicat de tip swing-out; P Achromat cu apertura numerica de 0.9;	Brosura Eclipse LV100N POL, pagina 8, rand: Condenser
			Polarizator: Fixat in partea de jos a suportului condensatorului;	Polarizator: Fixat in partea de jos a suportului condensatorului;	Brosura Eclipse LV100N POL, pagina 8, rand: Polarizers
			- Obiective: Plan Fluor Epi: - P 5x, apertura numerica de 0.15 si distanta de lucru de 23.5 mm 10x, apertura numerica de 0.3, distanta de lucru 17.3 mm 20x, apertura numerica de 0.45, distanta de lucru 4.5 mm 50x, apertura numerica de 0.8, distanta de lucru 1 mm 100x; apertura numerica de 0.9, distanta de lucru 1 mm	- Obiective: Plan Fluor Epi: - P 5x, apertura numerica de 0.15 si distanta de lucru de 23.5 mm 10x, apertura numerica de 0.3, distanta de lucru 17.3 mm 20x, apertura numerica de 0.45, distanta de lucru 4.5 mm 50x, apertura numerica de 0.8, distanta de lucru 1 mm 100x; apertura numerica de 0.9, distanta de lucru 1 mm	Brosura Eclipse LV100N POL, pagina 2, - CFI TU Plan Fluor EPI P
			Iluminator Episcopic: având o sursă de 12V/50W;	Iluminator Episcopic: având o sursă de 12V/50W;	Brosura Eclipse LV100N POL, pagina 5 – LV-UEPI-N
			Compensator: Standard de 1/4 λ, de quartz wedge;	Compensator: Standard de 1/4 λ, de quartz wedge;	Brosura Eclipse LV100N POL, pagina 8 rand: Compensators
			Consum de energie: 1.2A/75W;	Consum de energie: 1.2A/75W;	Brosura Eclipse LV100N POL, pagina 8 rand: power consumption
			- Camera: - rezoluție digitală – 16,25 megapixel; - dimensiunile senzor: 36.0 x 23.9 mm, - Sa genereze o rezoluție de 4908 x	- Camera: - rezoluție digitală – 16,25 megapixel; - dimensiunile senzor: 36.0 x 23.9	Prospect Microscope Camera – DS-Ri2, pagina 2 -

3264 fara a utiliza functii ca "schimbarea pixelilor" sau "pasuire pixeli" - conexiune USB 3.0; - Sensivitate ISO ridicata, ISO200 pana la ISO12800 - timp de expunere - 100 µsec - 120 sec; - montare obiectiv – F Montare; - Imagini live la 45 cadre pe secunde, - adaptor cu magnificare intermediara de 2.5; - format imagine: BMP, TIFF, JPEG etc.;	mm, - Sa genereze o rezolutie de 4908 x 3264 fara a utiliza functii ca "schimbarea pixelilor" sau "pasuire pixeli" - conexiune USB 3.0; - Sensivitate ISO ridicata, ISO200 pana la ISO12800 - timp de expunere - 100 µsec - 120 sec; - montare obiectiv – F Montare; - Imagini live la 45 cadre pe secunde, - adaptor cu magnificare intermediara de 2.5; format imagine: BMP, TIFF, JPEG etc.;	Specificatii
• Cerințe software: - BR MDI (Multiple Document Interface); - control cameră; - control microscop; - control periferic; - captură imagine în timp real; - captură imagine în interval de timp (T); - captură imagine în serie-Z,; - captură imagine din canale multiple (λ); - captură imagine din mai multe puncte (MP); - capturare imagine multidimensională – 4D și mai mult; - capturare imagine HDR; - captură AVI în regim real; - calibrarea obiectivului; - capturare meta-date; - filtrare imagine; - lista de căutare; - histogramă; - măsurare manuală;	• Cerințe software: - BR MDI (Multiple Document Interface); - control cameră; - control microscop; - control periferic; - captură imagine în timp real; - captură imagine în interval de timp (T); - captură imagine în serie-Z,; - captură imagine din canale multiple (λ); - captură imagine din mai multe puncte (MP); - capturare imagine multidimensională – 4D și mai mult; - capturare imagine HDR; - captură AVI în regim real; - calibrarea obiectivului; - capturare meta-date; - filtrare imagine; - lista de căutare; - histogramă; format imagine: BMP, TIFF, JPEG etc.;	Brosura Nis - Elements, pagina 3, - Coloana BR

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Semnăt: _____

Ofertantul: SC ELTA 90 MEDICAL RESEARCH SRL Adresa: srt. Nicolae G. Caramfil, nr. 22A, Sector 1, Bucuresti



BROȘURĂ

ECLIPSE LV100N POL Ci-POL

Polarizing Microscopes

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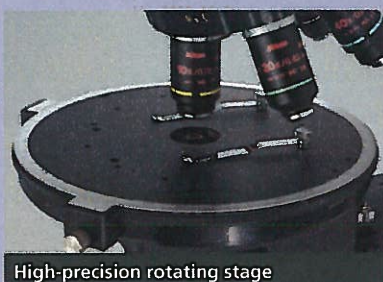
Page 1





Reversed centering quintuple nosepiece

Up to five objectives can be mounted and all objective positions are centerable. The DIN-compliant compensator slot accepts various compensators for qualitative or quantitative measurements.



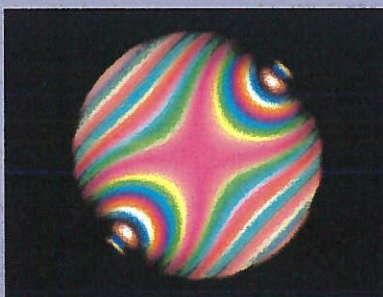
High-precision rotating stage

The LV100N POL stage is large, pre-adjusted, and click-stops in 45° increments. The smooth stage movement allows stable and easy rotation, providing high operability and high-quality polarized images. The underneath support for the stage table is close to the optical axis. Together with the steel cross roller guides, this provides outstanding stability and durability during regular use.



Intermediate tube

The intermediate tube incorporates a Bertrand lens as standard, enabling both the observation and capture of conoscopic and orthoscopic images. The Bertrand lens is focusable and centerable. The high precision slider-type analyzer can be rotated a full 360° with a precision vernier scale. A P-LC tint plate slider with full and quarter wave plates and an empty space is available.



Conoscopic image of mica / CFI Achromat P 40X

The highest level of optical quality,

- The low-power-consumption 50W light source is brighter than a 100W lamp, and reduces heat-induced focus drift and energy consumption.
- High-precision centerable nosepiece and stage with smooth, accurate movement. (LV100N POL only)
- 30mm long focus stroke accepts tall samples.



ECLIPSE CI-POL
(Diascopic illumination)

ECLIPSE CI-POL
(Diascopic/Episcopic illumination)

Objectives for polarizing observation

CFI Achromat P objective series (for diascopic illumination)

The unique Nikon CFI60 objectives successfully deliver longer standard working distances and high numerical apertures, offering superb image flatness, contrast and cost performance.



CFI TU Plan Fluor EPI P objective series (for diascopic/episcopic illumination)

The CFI TU Plan Fluor EPI P series of CFI60-2 objectives produce pin-sharp aberration-free images regardless of magnification.



Nikon CFI optics employ an eco-glass that is manufactured with no harmful substances such as lead and arsenic.

operability and stability for polarizing microscopy



1



2



3



ECLIPSE LV100N POL
(Diascopic illumination)

ECLIPSE LV100N POL
(Diascopic/Episcopic illumination)



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Pag 3

ECLIPSE LV100N POL Diascopic illumination type

Outstanding optical performance, perfect for a wide variety of imaging applications and polarizing techniques

Nikon has developed a high-intensity 50W halogen light source (with dedicated lamphouse) that provides greater brightness than a conventional 100W halogen light source. Brightness is increased by approximately 20 to 40% with objective magnifications of 50X and higher. This light source consumes less electrical power and generates very little heat, greatly reducing focus drift resulting from light source heat.

- Microscope body is designed to realize high robustness.
- Unique stage mount design ensures exceptional stability.
- Nosepiece comes with a DIN standard compensator slot.
- All five objective positions on the nosepiece are centerable.
- Uses CFI60 optics, realizing both high NA and longer standard working distances.
- A clamp-type upper limit focusing mechanism makes for easy, safe sample exchange, protecting both sample and optics from collision damage.

Why is 50W brighter than 100W?

Brightness is not determined by wattage. Nikon's unique light source design achieves greater brightness by optimizing the lamp filament size and improving pupil illumination fulfillment. The latter has been achieved by optically expanding the size of the light source with a mirror in the lamphouse. This has resulted in a 50W light source that is brighter than a 100W lamp—about 40% brighter with diascopic illumination*.

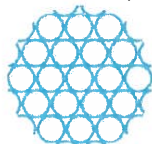
*With 100X objectives.

Uniform brightness with diascopic illumination

Nikon's unique fly-eye lens has been employed in diascopic illumination optics. This enables high quality imaging with no variations in luminescence throughout the view field.



Concept of Fly-eye Lens



Fly-eye lens



Ordinary lens



ECLIPSE Ci-POL Diascopic illumination type

A compact polarizing microscope that balances optical performance and ease of use

- Slim and compact, an excessively large working area is not necessary.
- Nosepiece uses the same DIN standard compensator slot design as LV100N POL.
- All five objective positions on the nosepiece are centerable.
- Uses CFI60 optics, realizing both high NA and long standard working distances.
- A clamp-type upper limit focusing mechanism makes for easy, safe sample exchange, protecting both sample and optics from collision damage.
- Excellent cost effective and precision manufacturing is balanced with superb basic performance for a polarizing microscope.
- Built-in capture button allows easy imaging with the DS-Fi3 and DS-Ri2 cameras (Please see page 6).



Page 4



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ECLIPSE LV100N POL Diascopic/Episcopic illumination type
ECLIPSE Ci-POL Diascopic/Episcopic illumination type

Accomplishes advanced polarizing microscopy under both diascopic and episcopic illumination

Both diascopic and episcopic polarizing observations are possible by mounting the LV-UEPI-N Universal Epi-illuminator*. Switching the illumination technique is a simple operation. The epi-illuminator uses a Nikon 12V50W light source that provides brighter illumination than a 100W lamp. The noise-terminator mechanism provides sharp images with high S/N ratios by eliminating stray light. With the optional universal-type nosepiece and DIC accessories including objectives, episcopic differential interference contrast (DIC) microscopy is also possible.

* When used with the Ci-POL, LV-UEPI-N requires an external power supply.



ECLIPSE Ci-POL
(Diascopic/Episcopic illumination type)

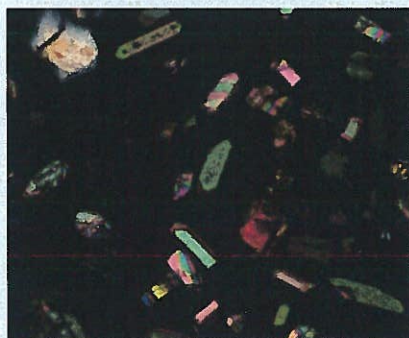


ECLIPSE LV100N POL
(Diascopic/Episcopic illumination type)

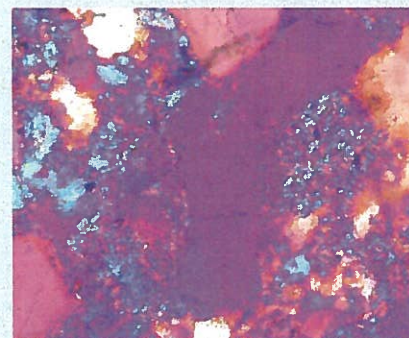
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Page 5

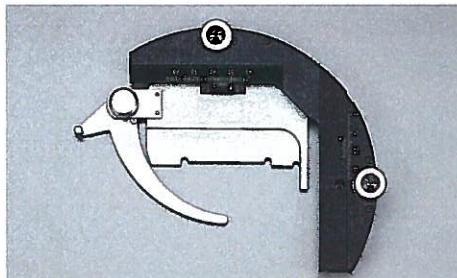
Optional Accessories for Polarizing Observations

Attachable mechanical stage

To improve microscopy efficiency, an attachable mechanical stage can be mounted on the rotating stage to rigidly hold and move the sample.

Cross travel: 35 x 25 mm

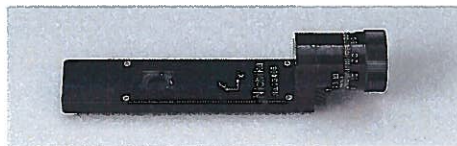
Minimum increment. increment: 0.1mm on the vernier



Berek compensator

Inserted into the nosepiece slot, this compensator permits retardation measurements from 0 to 1800 nm.

Manufactured by Nichika Corporation.



Senarmont compensator

Inserted into the intermediate tube. In addition to the standard use 1/4 λ plate and a 546 nm (1 λ) tint plate (1st order red plate), a Senarmont compensator is also available as an option, for retardation measurements from 0 to 1 λ .



Quartz wedge compensator

Inserted into the intermediate tube, this compensator permits retardation measurements from 1 to 6 λ orders.



IF 546/12 retardation filter

High-precision interference filter with a 546 nm central wavelength and 12 nm FWHM (full-width at half maximum). Used to increase the precision of retardation measurements.

Digital Camera for Microscopes

When the DS-Fi3 and DS-Ri2 cameras are connected directly to a PC, the NIS-Elements software allows the acquisition, processing, measurement and analysis of images, as well as data management and report creation.

C-mount camera

DS-Fi3 Microscope Camera

Equipped with a 5.9-megapixel CMOS sensor, the DS-Fi3 enables fast 15 fps acquisition of high definition images of up to 2880 x 2048 pixels with superior color reproduction for vivid polarized images. It also provides smooth live image movement and high sensitivity imaging of weak-light polarization samples.



F-mount camera

DS-Ri2 Microscope Camera

Equipped with a 16.25-megapixel FX-format CMOS sensor for digital SLR cameras, the DS-Ri2 provides high definition images of up to 4908 x 3264 pixels, as well as high sensitivity, accurate color reproduction of interference colors and fast frame rates of up to 45 fps (1636 x 1088 pixels).

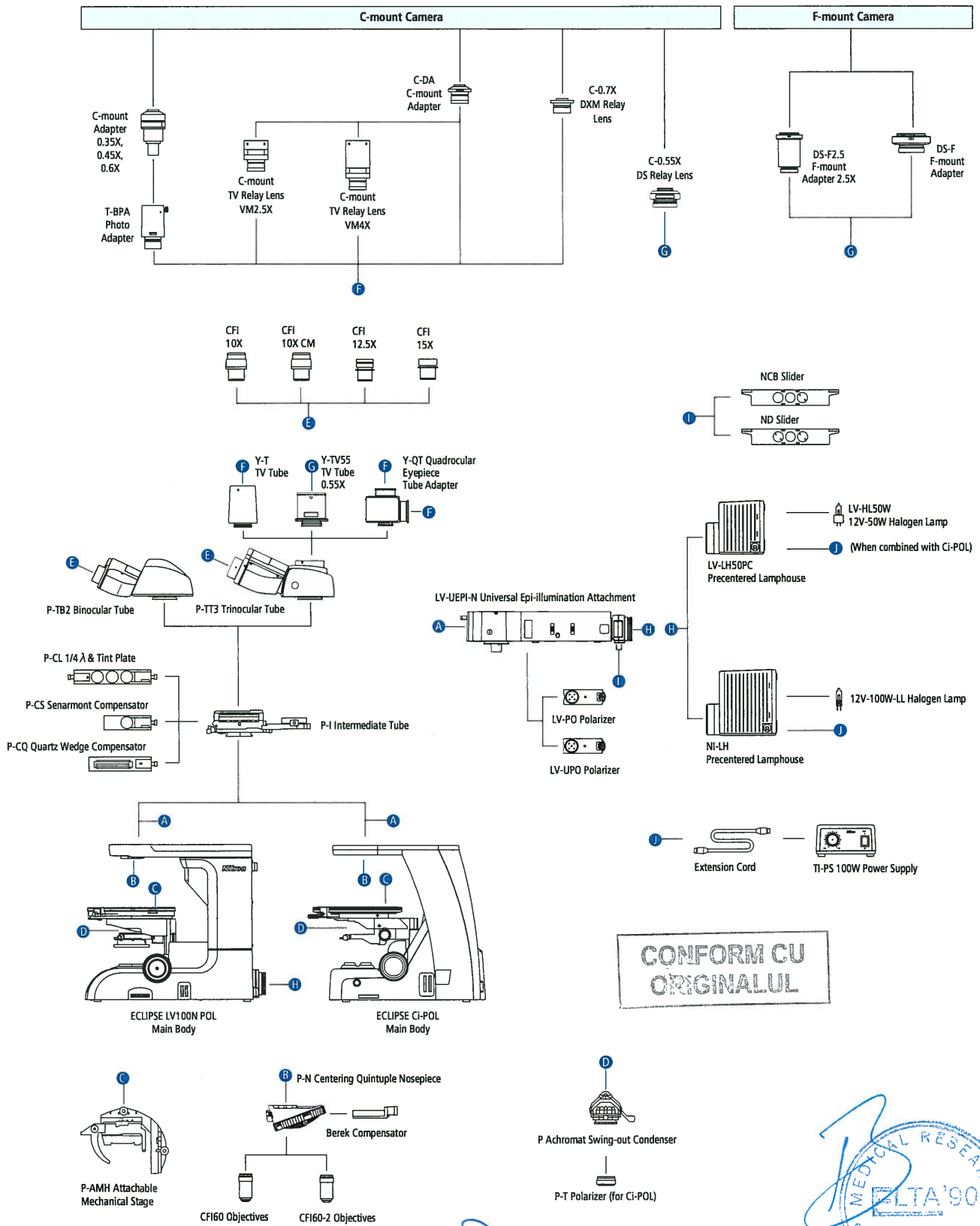


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Page 6

System Diagram



Page 7

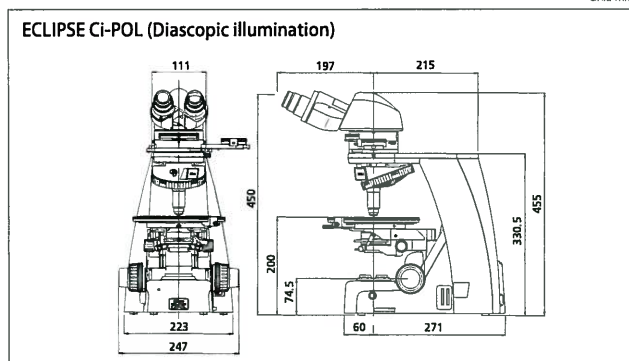
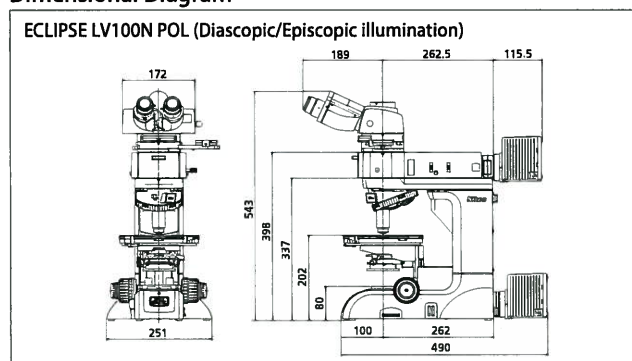


Specifications

		ECLIPSE LV100N POL	ECLIPSE CI-POL
Main body	Optical system	CFI60 infinity	
	Illumination	12V-50W halogen lamp; 12V-50W DC transformer built-in; Diascopic/episcopic illumination changeover switch; Fly-eye lens; NCB11, ND8 filters built-in; 12V-100W type optional	6V-30W halogen lamp; 6V-30W transformer built-in; ND8, ND4 filters built-in
	Focusing	Coaxial coarse/fine focus knob; Focus stroke: 30mm; Coarse: 14mm per rotation; Fine: 0.1mm; Minimum reading: in 1µm increments	Coaxial coarse/fine focus knob; Focus stroke: 30mm; Coarse: 9.33mm per rotation; Fine: 0.1mm; Minimum reading: in 1µm increments
Eyepieces (F.O.V., mm)		CFI 10X (22), CFI 10X CM (22), CFI 12.5X (16), CFI 15X (14.5)	
Tubes		P-TT3 Trinocular Tube for polarizing microscopy; P-TB2 Binocular Tube for polarizing microscopy	
Intermediate tube		Built-in focusable Bertrand lens removable from optical path; Conoscopic/Orthoscopic observations switchable; Analyzer built-in; Accessory plate/compensator slot	
Analyzer		360° rotary dial; Minimum reading angle 0.1°	
Nosepiece		Centering quintuple nosepiece (detachable); DIN slot	
Stages		Top-grade dedicated circular graduated stage Rotatable 360° horizontally; can be fixed at a specific position; Graduated 360° (in 1° increments); Click stops each 45°; Attachable mechanical stage: 35 x 25 mm travel; vernier 0.1mm	Ball bearing rotary stage; Rotatable 360° horizontally; can be fixed at a specific position; Graduated 360° (in 1° increments); Rotation clamp equipped; Attachable mechanical stage: 35 x 25 mm travel; vernier 0.1mm
Condenser		Dedicated strain-free swing-out type; P Achromat NA 0.9	
Polarizers		Fixed to the bottom of the condenser holder; with scale markings	No scale markings
Objectives (Polarizing sets)		CFI Achromat P 4X, P 10X, LWD P 20X, P 40X, P 100X Oil CFI TU Plan Fluor EPI P 5X, P 10X, P 20X, P 50X, P 100X	
Episcopic illuminator		LV-UEPI-N Universal Epi-illuminator (The LV100N POL accommodates a 12V-50W illuminator transformer)	LV-UEPI-N Universal Epi-illuminator (The CI-POL requires an external power supply)
Compensators		P-CL Standard 1/4 λ & tint plate, quartz wedge or Senarmont compensator can be inserted into intermediate tube slot	
Power consumption		1.2A/75W	0.8A/38W
Weight		Approx. 17kg (standard trinocular set)	Approx. 14kg (standard binocular set)

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Dimensional Diagram



Images courtesy of:
Dr. Kazuhiro Suzuki and Dr. Takenori Kato, Center for Chronological Research, Nagoya University (● on page 3, ● on page 5)
Ron Sturm, Construction Technology Laboratories, Inc., U.S.A. (● on page 5)
Mike Davidson, Florida State University, U.S.A. (● on page 3, ● on page 5)

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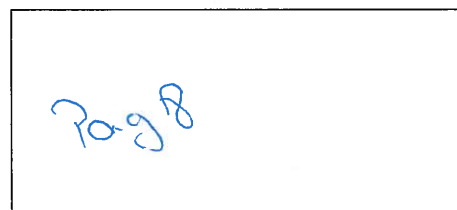
NIKON GMBH

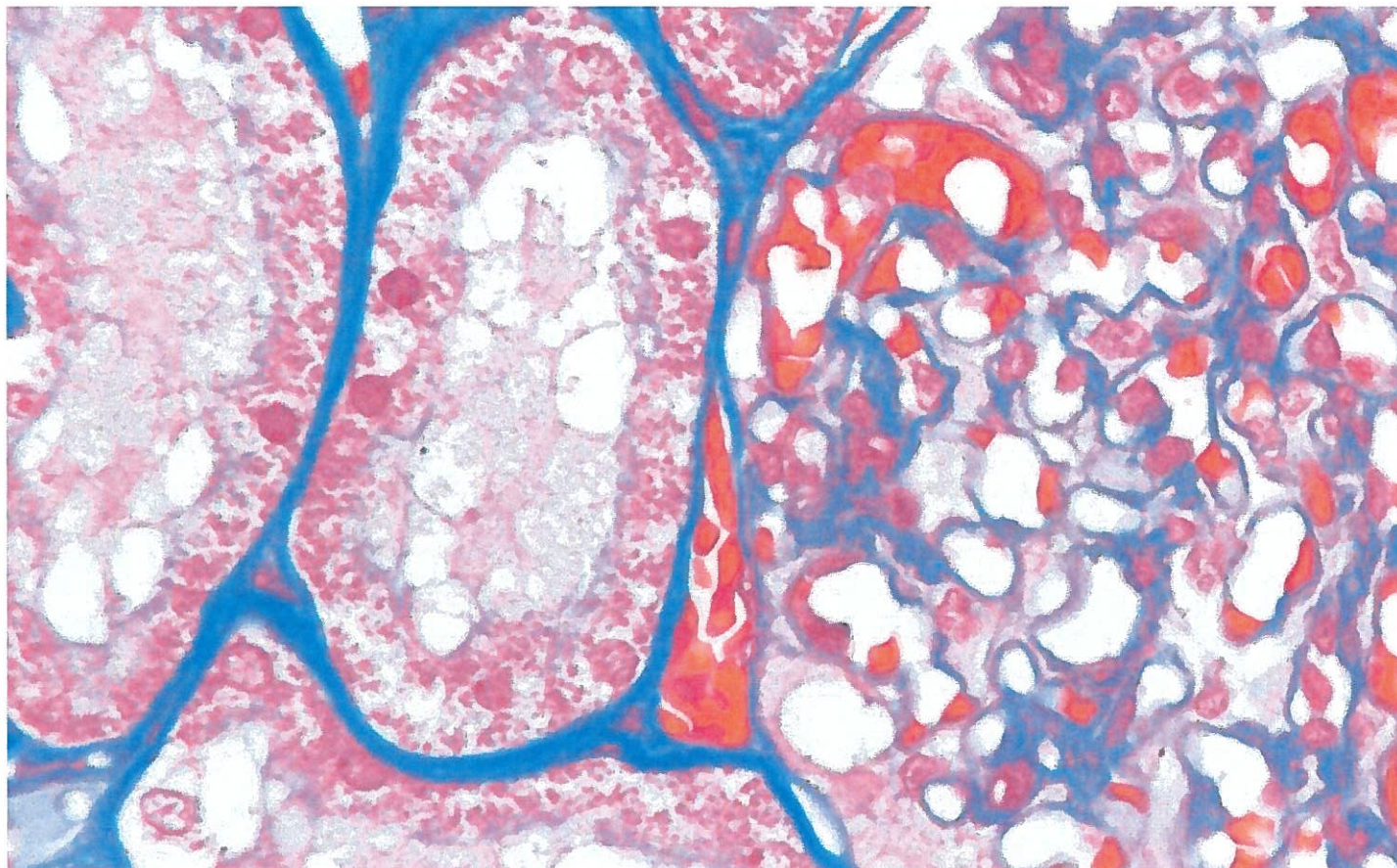
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PROSPECT

DS-Ri2

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Microscope Camera

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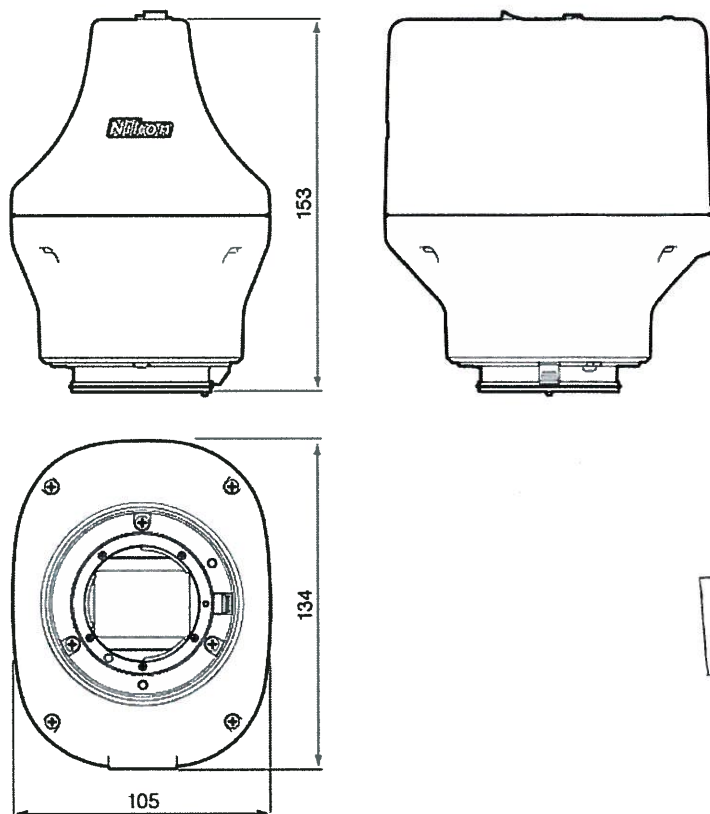
- [Overview / Key Features](#)
- [Specifications](#)

Specifications

Image sensor	Nikon FX-format, Color CMOS sensor / Size: 36.0x23.9mm Effective 16.25 megapixels
Recordable pixels	4908x3264 pixel (full-pixel), 1636x1088 pixel (3x3 pixel averaging)
ISO sensitivity (recommended exposure index)	Standard: equivalent to ISO 200 (Selectable from ISO200 to 12800 equivalent)
Live display mode	Full-pixel 4908x3264 pixel (max 6fps) / 3x3 pixel averaging 1636x1088 (max 45fps)
Lens mount	F mount
Exposure time	100 µsec to 120 sec
Image format	BMP, TIFF, JPEG, etc., selectable in NIS-Elements
Interface	USB3.0 (computer control connection) x1, External sync input/output x1
Power supply	AC100-240V 50/60Hz
Power consumption	13W
Dimensions	105 (W) x 134 (D) x 153 (H) mm
Weight	1200g
Operating environment	0-40°C, 60% RH max. (without condensation)



Diagrams



unit:mm

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Product Brochure


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Cameras

- [DS-Ri2](#)
- [DS-Qi2](#)
- [DS-Fi3](#)
- [DS-L4 Controller](#)

Related Products

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Page 2

Imaging Software NIS-Elements



Nikon
100th
anniversary

Imaging Software
NIS)Elements

Advanced Solutions for your Imaging World

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pag 1

Nikon offers a total software solution for image capturing, archiving, and analysis

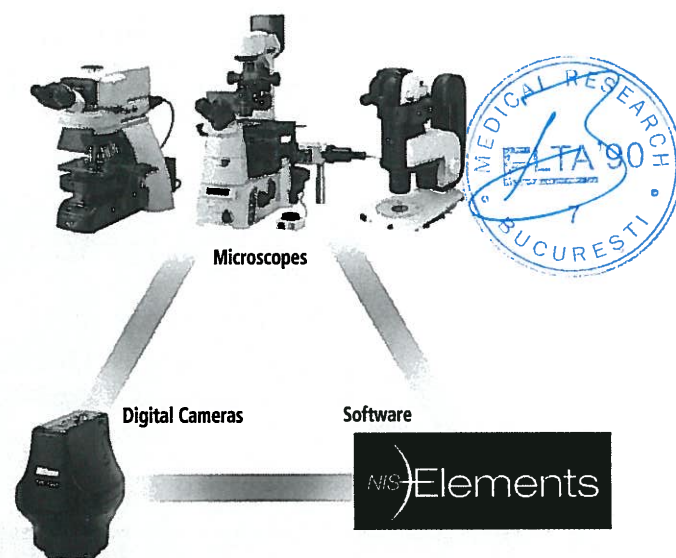
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Why NIS-Elements?

NIS-Elements is an integrated software imaging platform which delivers comprehensive control of microscopes and peripheral devices, image capturing, documentation, image analysis and data management of up to six dimensions. This system contributes to experiment efficiency with intuitive image analysis features and database building capabilities developed to handle archiving and management of large numbers of multidimensional image files. Unified control of the entire imaging system offers significant benefits to users for cutting-edge research, such as live cell imaging.

Total Imaging Solution

Designed to serve the needs of advanced bioresearch, clinical, industrial and documentation professionals, NIS-Elements provides a totally integrated solution for users of Nikon and other manufacturers' accessories by delivering automated intelligence to microscopes, cameras, and peripheral components. The software optimizes the imaging process and workflow and provides the critical element of information management for system-based microscopy.

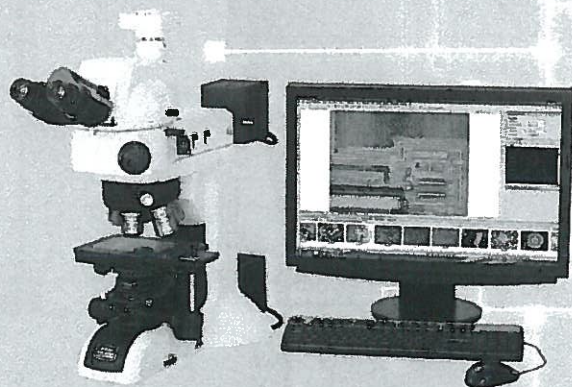


Highest Quality Optical Performance

The world-renowned Nikon CFI60 infinity optical system has effectively set a new standard for optical quality by providing longer working distances, higher numerical apertures, and the widest magnification range and documentation field sizes. Nikon's new objectives and accessories are specifically engineered for digital imaging.

Diverse Line of Powerful Digital Cameras

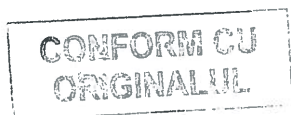
Nikon offers a full line of digital cameras, addressing the varied needs of users in multiple disciplines. Each Nikon digital camera is designed to work seamlessly with Nikon microscopes, peripherals, and software. With Nikon Digital Sight (DS) series cameras, even novice users can take beautiful and accurate microscopic images. For the advanced researcher, high resolution image capturing and versatile camera control is fast and simple.



AR NIS-Elements AR is optimized for advanced research applications, featuring fully-automated acquisition and device control through full 6D (X, Y, Z, Lambda (Wavelength), Time, Multipoint) image acquisition and a wide range of image analyses.

Br NIS-Elements BR is suited for standard research applications, photodocumentation of fluorescent samples and image analysis, including intensity and counting measurements. It features acquisition and device control through 4D (up to four dimensions can be selected from X, Y, Z, Lambda (Wavelength), Time, Multipoint) acquisition.

D NIS-Elements D supports color documentation requirements in bioresearch, clinical and industrial applications, with basic measuring and reporting capabilities.



Main Features

	AR MDI (Multiple Document Interface)	BR MDI (Multiple Document Interface)	D SDI (Single Document Interface)
Window style	○	○	—
Dark color scheme	—	—	○
Industrial simple GUI	○	○	○
Camera control	○	○	○
Microscope control	○	○	○
Nikon made peripheral control	○	○	○
Non-Nikon peripheral control	○	○	○
Live image capture	○	○	○
Time-lapse image capturing (T)	○	○	△
Z-series image capturing (Z)	○	○	○
Multichannel image capturing (λ)	○	○	—
Multipoint image capturing (MP)	○	○	○
Multidimensional image capturing	● Up to 6D	● Up to 4D	—
Stimulation experiment	●	—	—
RAM capture	○	—	—
HDR image capture	○	●	●
AVI live-stream capture	○	○	○
Objective calibration	○	○	○
Capturing data savings (Meta-data)	○	○	○
Image filtering	○	△	△
Binary	○	△	▲
LUT (look up table)	○	○	○
Histogram	○	○	○
Manual measurement	○	○	○
Auto measurement	○	○	●
Intensity line profile	○	○	○
Intensity surface plot	○	○	○
Time (intensity) measurement	○	●	—
3D measurement	●	▲	▲
Volume measurement	○	—	—
Database	●	●	●
Macro	○	△	△
Advanced interpreter	○	●	●
Report generator	○	○	○
Live compare	○	●	●
Volume view	○	△	△
EDF (Extended depth of focus)	●	●	●
3D surface view	●	●	●
Ratio view	○	—	—
2D real time deconvolution	●	—	—
2D deconvolution	●	—	—
3D deconvolution	●	—	—
3D blind deconvolution	●	—	—
TTL/analog IO	●	●	●
Object classifier	●	—	—
2D/3D object tracking	●	—	—
Calcium & FRET	●	—	—
General analysis	●	—	—
HC Template	●	—	—
JOBS Editor	●	—	—
N-SIM analysis	●	—	—
N-SIM offline analysis	●	—	—
N-STORM analysis	●	—	—
N-STORM offline analysis*	●	—	—
Metallurgical analysis	—	—	●
Illumination sequence	●	—	—
Stage incubator control	●	—	—
Dual camera support	●	—	—

○ : Full function △ : Limited function —: Not available ● / ▲ : Option

* N-STORM analysis is required.

Page 3